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Class	Subclass
ISSUE CLASSIFICATION	

PATENT NUMBER

6330755

U.S. REISSUE Patent Application

O.I.P.E.	O.G. PUBLICATION DATE	REISSUE PATENT DATE
SCANNED  Q.A. <u>HA</u>	<u>04/11/2011</u>	

APPLICATION NO. 10/066747	CONT/PRIOR D F	CLASS 034	SUBCLASS 444-40	ART UNIT 3749	EXAMINER O'Malley Wilson, Pam
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APPLICANTS

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TIME

Vacuum processing operating method

with wafers, substrates
method, and/or semiconductors

PAW 8/31/03

PTO-2040
12/99

☒ SURRENDER OF ORIGINAL PATENT  (Exr. Initials) ORIGINAL PATENT NUMBER 6,330,155

[illegible]

<input type="checkbox"/> TERMINAL DISCLAIMER	DRAWINGS			CLAIMS ALLOWED	
	Sheets Drwg. 1	Figs. Drwg. 2	Print Fig. 1	Total Claims 32	Print Claim for O.G. 1
<input type="checkbox"/> The term of this patent subsequent to _____ (date) has been disclaimed.	Kathryn S. O'Malley 5/25/07 (Assistant Examiner) (Date)			NOTICE OF ALLOWANCE MAILED	
<input type="checkbox"/> The term of this patent shall not extend beyond the expiration date of U.S. Patent. No. _____	[Signature] Ra S. Lazarus Supervisory Patent Examiner Group 2700 _____ 6/10/07 (Primary Examiner) (Date)			ISSUE FEE	
<input type="checkbox"/> The terminal _____ months of this patent have been disclaimed.				Amount Due	Date Paid
FINAL SPRE REVIEW [Signature] 1/23/06 (INITIALS)				ISSUE BATCH NUMBER	

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